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U.S. UTILITY Patent Application

PATENT NUMBER and
ISSUE DATE

APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
10026419	12/26/2001	430	322	1752	Chadco-Davis

****APPLICANTS:** Kawano Kenji; Ito Shinichi; Shiobara Eishi; Kawamura Daisuke;
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****CONTINUING DATA VERIFIED:** *none*

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**** FOREIGN APPLICATIONS VERIFIED:** *W*

JAPAN 2000-394354 12/26/2000

JAPAN 2001-011299 01/19/2001

JAPAN 2001385349 12/19/2001

PG-PU3	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>
Foreign priority claimed	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no	ATTORNEY DOCKET NO
35 USC 119 conditions met	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no	04329.2718
Verified and Acknowledged Examiners's initials <i>WD</i>		
TITLE : Apparatus for processing substrate and method of processing the same		

U.S. DEPT. OF COM. / PAT. & TM-PTO-432 (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Total Claims	Print Claim for O.S.
ISSUE FEE		DRAWING	
Amount Due	Date Paid	Sheets Drawn	Figs. Drawn
		Print Fig.	
<input type="checkbox"/> TERMINAL DISCLAIMER		Application Examiner	
		PREPARED FOR ISSUE	
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